

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in this application:

LISTING OF CLAIMS:

1. (Currently Amended) A micromechanical component, comprising:
a supporting body;
at least one at least partially unsupported membrane connected to the supporting body;
at least one stabilizing element provided in an unsupported area on some areas of a surface of the at least one membrane,
wherein the at least one membrane extends continuous over an entire recess etched in the supporting body, and a portion of the at least one stabilizing element contacts only the membrane for a part less than a whole ~~length~~ depth of the recess of the membrane and a portion of the at least one stabilizing element is positioned between the supporting body and the at least one membrane, and
wherein at least a part of the stabilizing element is exposed to the recess etched in the supporting body wherein the at least one stabilizing element includes at least a ring-shaped skirt arranged around one of recesses and etching holes in the at least one membrane, and
wherein the micromechanical component is configured as a thermal membrane sensor and the at least one stabilizing element is configured to counteract a deformation of the at least one membrane.

Claims 2 and 3. (Canceled).

4. (Original) The micromechanical component according to claim 3, wherein:
the deformation includes one of a warping, a propagation of cracks, and a propagation of stresses in the at least one membrane.
5. (Previously Presented) The micromechanical component according to claim 1, wherein:
the at least one stabilizing element includes one of:
a web,

a plurality of webs,
parallel webs,
an arrangement of webs configured in a mesh,
an arrangement of webs configured in a grid,
a web designed as a ring,
a plurality of webs designed in concentric rings, and
a stabilizing area designed in the shape of one of a tongue and a rod.

6. (Original) The micromechanical component according to claim 1, wherein:
the at least one stabilizing element includes at least one of:

a ring-shaped skirt arranged around one of recesses and
etching holes in the at least one membrane, and
a stabilizing surface in corner areas of the at least one
membrane.

7. (Original) The micromechanical component according to claim 1, wherein:
the at least one stabilizing element is arranged on one side of the at least one
membrane facing the supporting body.

8. (Original) The micromechanical component according to claim 1, wherein:
the at least one stabilizing element is in direct contact with the at least one
membrane and is bonded thereto in at least some areas in the unsupported area.

Claim 9. (Canceled).

10. (Original) The micromechanical component according to claim 1, wherein:
the supporting body includes a silicon body.

11. (Original) The micromechanical component according to claim 1, wherein:
the at least one membrane includes a silicon compound and has a thickness
of 10 nm to 10 μ m.

12. (Original) The micromechanical component according to claim 11,
wherein:

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the silicon compound includes one of a silicon nitride layer, a silicon carbide layer, and a silicon dioxide layer.

13. (Previously Presented) The micromechanical component according to claim 1, further comprising:

a circuit structure positioned on the at least one membrane.

14. (Original) The micromechanical component according to claim 13, wherein:

the circuit structure includes at least one of at least one thermocouple and a sensitive component of a sensor element.

15. (Original) The micromechanical component according to claim 1, wherein:
a thickness of the at least one stabilizing element is between 10 nm and 5 μm .

Claims 16 to 24. (Canceled).